

**Vacuum machining system having a process chamber with a vacuum regulating valve**

**Abstract**

5

Vacuum machining system (1), comprising a vacuum chamber (10) and a vacuum regulating valve (20). The vacuum valve (20) has a first valve seat (21a), which has a first valve opening (22a) defining a first opening axis (O) and a first sealing surface  
10 extending around the first valve opening (O), and a first valve plate (23a) with a first contact surface corresponding to the first sealing surface. The vacuum machining system further comprises a drive unit (30), which is designed in such a way and is coupled to the first valve plate (23a) in such a way that the  
15 latter can be moved at least from an open position to a closed position and back again. The first valve seat (21a) is arranged within the vacuum chamber (10) and divides the vacuum chamber (10) into a main process chamber (11) for machining the substrate and into a secondary process chamber (12). The first sealing  
20 surface extends orthogonally to the first opening axis (O) and points in the direction of the secondary process chamber (12). The first valve plate (23a) is movably arranged in the secondary process chamber (12).

25

Fig. 1